

matter therein.

Please amend claim 17 as follows:

*D1*  
*sub*  
*E1*

17. (Amended) An electroactive device providing large mechanical output displacements, comprising:

a layered structure having a prestressing layer having a convex surface, and a piezoelectric layer having a concave surface, the convex surface of the prestressing layer being bonded onto the concave surface of the piezoelectric layer such that the prestressing layer is in tension and imparts a prestress on the piezoelectric layer such that [and] the piezoelectric layer is in compression.

#### REMARKS

Claims 9-16 have been canceled. Claims 17-24 have been rejected under 35 U.S.C. 103(a) as unpatentable over Haertling in view of Corwin. As amended, independent claim 17 recites a electroactive device comprising a layered structure having the convex surface of the prestressing layer bonded to the concave surface of the piezoelectric layer and imparting a prestress on the piezoelectric layer such that the piezoelectric layer is in tension.

In contrast, Haertling's invention is a monolithic, curved piezoelectric device that is internally asymmetrically stress biased (see col.1, lines 18-20). Haertling states that none of the prior art approaches, including bonding various materials to a piezoelectric element (see col. 2, lines 30-67), could produce a piezoelectric device having the desired functionality, i.e., including the ability to produce relatively large strains and sustain moderate loads, as well as have an asymmetrical internal stress bias to produce above-plane axial displacement (see also col. 4, lines 19-26). Thus, Haertling explicitly teaches away from a bonded, layered structure to produce the desired internal asymmetrical stress. Further, Haertling's ceramic device is a monolithic, concave-shaped wafer in which the first side (i.e., the concave side) of the